Elastomeric waveguide on-chip coupling of an encapsulated MoS$_2$ monolayer

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Abstract

We propose a robust photonic platform for encapsulation and addressing of optically active 2D- and nano-materials. Our implementation utilises a monolayer of MoS$_2$ transition metal dichalcogenide embedded in an elastomeric waveguide chip. The structure is manufactured from PDMS using soft-lithography and capable of sustaining a single mode of guided light. We prove that this setup facilitates addressing of the 2D material flake by pumping it with polarised laser light and gathering polarisation-resolved photoluminescence spectra with the extinction ratio of 31, which highlights the potential for selection-rule dependent measurements. Our results demonstrate improved handling of the material and experimental simplification compared to other techniques.
Furthermore, inherent elasticity of the host provides an avenue for direct mechanical coupling to embedded materials.

Introduction

Advances in the fundamental understanding of transition metal dichalcogenides (TMDs) including their excitonic properties, exciton-phonon coupling, optical selection rules and valley degree of freedom, position them as attractive candidates for components of devices in novel photonic applications. Monolayer materials are fragile and difficult to handle due to the micrometer footprint and their tendency to crumple. In order to incorporate them in the existing photonic systems, there is a need for packaging in the form of a robust platform for handling and testing of the material. Planar photonic waveguide chips capable of confining light on the micrometer scale are a natural candidate for such a platform, offering transmission of visible light, polarisation selectivity and shielding from environmental influence. While this is challenging to achieve with traditional semiconductor or glass waveguide structures, we propose that a photonic device fabricated in an elastomer can serve as a host for encapsulation of the monolayers and their heterostructures. Using the proposed geometry, we show it is feasible to confine an optically active 2D material within the mode of guided light, allowing for the propagation of linearly polarised light in the plane of the monolayer. The polarisation of light in this system can be changed such that exciton states with different optical selection rules (e.g. dark and bright excitons) can be independently accessed. Embedding the material of interest in an elastomer gives an added benefit of direct mechanical coupling by performing either global or local deformation of the chip.

Here, we describe a proof-of-concept device, utilising a monolayer of MoS$_2$ encapsulated within the mode of light guided in a polydimethylsiloxane (PDMS) chip. Artistic representation of the experimental sample (Figure 1a) shows an MoS$_2$ flake inserted between the two layers of PDMS. Different refractive indices of the layers (1.4320 and 1.4311, simulated), together with the geometry of the top ridge, create a light-guiding structure capable of sus-
Figure 1: Elastomeric waveguide structure with optically active material encapsulated within the guided mode of light. (a) Artistic representation of the monolayer of MoS$_2$ encapsulated within the waveguide structure comprised of two layers of elastomer with different densities. Call-out shows the schematic representation of addressing (green arrow) and collection (red arrow) geometry with respect to the MoS$_2$ monolayer. (b) Photoluminescence spectrum collected from the encapsulated MoS$_2$ monolayer. Physical origins of the individual components of the spectrum are deduced by fitting the Gaussian functions, which correspond to: neutral B-exciton ($B_0$), substrate Raman doublet (R), neutral A-exciton ($A_0$), charged A-exciton ($A_-$), defect emission ($X_D$). (c) Optical microscope image ($\times100$ magnification) of the encapsulated flake. White dashed lines outline the flake and the boundary between the monolayer and bulk material. Green dashed lines outline the edges of the waveguide (5 $\mu$m width). (d) Flake illuminated with 532 nm pump. (e) Optical microscope image of the PL emission. Pump is blocked with a long-pass filter. Magenta dot indicates the probing region, from which the PL spectrum has been collected during the polarisation dependence experiment.
taining a single mode of radiation (see inset in Figure 2 for an image of the guided mode). Positioning a flake of 2D material within the mode of the guided light allows for efficient coupling. Here, we demonstrate this experimentally for a flake of MoS\textsubscript{2} by exciting it through the waveguide and performing room temperature measurement of the photoluminescence spectrum while varying the polarisation of incident light.

**Methods**

The elastomeric waveguide chip is fabricated out of polydimethylsiloxane (PDMS) in a two-step soft lithography process,\textsuperscript{9} with an additional step for material encapsulation. A lithographic mould is prepared by defining 5µm by 1.6µm waveguides on a silicon wafer using laser direct-write in the AZ photoresist. The PDMS liquid precursor is spun onto the mould and cured at 150°C to create a 5µm thick high-density layer. The MoS\textsubscript{2} flake is transferred to the cured PDMS layer at the location of a waveguide, using dry-stamping technique.\textsuperscript{10} 1 mm of PDMS liquid precursor is then poured on the top of the structure and cured at 70°C to form a low-density layer and provide structural base for the chip. The chip is then peeled off the silicon substrate and end-faces are cut using a microtome blade to enable coupling of an optical fibre. Optical microscope images of the encapsulated flake are shown in Figure 1c to e.

The experimental setup for the excitation and collection of PL spectra is shown in Figure 2. 532 nm laser light is coupled to a single-mode fibre, which is cut and stripped at one end to expose the core and cladding. The exposed end is mounted on a micrometre stage (Newport ULTRAAlign XYZ + yaw, pitch, roll) and aligned to couple to the chip waveguide that encapsulates the MoS\textsubscript{2} flake. Coupling is optimised by maximising the transmitted power collected by the imaging objective on the opposite end of the chip (×20). The incident light couples to the MoS\textsubscript{2} monolayer and the resulting photoluminescence is collected by a high NA top-down objective (×100), after passing through the long-pass filter to eliminate excitation wavelength. A half-waveplate, positioned in front of the laser, is used to rotate
the polarisation of light interacting with the MoS$_2$ flake. A quarter-waveplate is introduced to compensate for any circular polarisation that may be introduced by the fibre and ensure linear polarisation at the flake location.

Figure 2: (a) Photoluminescence experimental setup (chip side-view perspective). Exposed fibre tip, the waveguide chip and the imaging microscope are each mounted independently on micrometre stages for alignment. The top-down microscope is part of a larger spectroscopy setup (custom-designed NTEGRA system by NT-MDT). (b) Microscope image of the fibre tip coupling 532 nm pump laser to the waveguide chip. 125 µm diameter cladding of the fibre is visible, together with three 5 µm waveguides on the chip. (c) Experimental TEM mode of the transmitted light, measured at the end-face of the waveguide chip (see arrow).

Results

A monolayer of MoS$_2$ is pumped with in-plane 532 nm laser light to induce the primary photoexcitations (excitons) (Figure 4a). The resultant photoluminescence spectrum reveals the typical characteristics of monolayer MoS$_2$, which mainly consist of the ground exciton peak\textsuperscript{11} originating from the direct optical transition at the K and K points of the Brillouin zone.\textsuperscript{12,13} The main photoluminescence peak is made of two contributions: neutral (A$_0$) and charged (A$_-$) excitons\textsuperscript{14,15} (see Figure 1b). Minor contributions at the higher and lower energies come from the B exciton and defect states, respectively.\textsuperscript{16,17} The spectrum can be fitted with Gaussian curves corresponding to these exciton species to a good approximation.
since the excitonic linewidth is dominated by inhomogeneous broadening at room tempe-

ature.\textsuperscript{18} The neutral exciton peak is found to be at 667 nm, which is consistent with that of MoS\textsubscript{2} on other substrates, indicating good quality of the encapsulated material.

![Figure 3](image)

**Figure 3:** Photoluminescence maps of the flake area obtained with NTEGRA (NT-MDT) piezo-controlled spectrometer. (a) Integrated photoluminescence in the vicinity of the waveguide ridge. White dashed lines indicate edges of the waveguide. Irregularities in the mono-layer are visible in the waveguide path. (b) Linewidth broadening. (c) Peak position showing a strong correlation with waveguide geometry. See text for explanation.

Encapsulated flake is investigated in detail by spatial mapping of the photoluminescence spectrum by normal excitation, which shows the distribution of the integrated photolumi-

nescence, linewidth broadening and the peak position for the 620–720 nm spectral range (Figures 3a, b and c respectively). Figure 3a reveals the integrated photoluminescence spec-

trum map for the area of the flake within and around the edges of the waveguide ridge, with the variations that can be attributed to the spatial inhomogeneity of the flake due to the transfer process (e.g. corrugation, wrinkles or cracks). There is a correlation between the linewidth distribution and the photoluminescence intensity (compare Figure 3a and b), with narrow emission implying high area and intensity.

The map of the peak distribution (Figure 3c) shows a strong correlation with the waveguide geometry, with the two regions of interest separated by the edges of the waveguide ridge. Photoluminescence peak undergoes a red shift of around 20 nm (\(\sim 55 \text{ meV}\)) when going from the outer region towards the waveguide ridge. Similar modifications of the optical properties have been reported for uniaxially\textsuperscript{19} and biaxially\textsuperscript{2} strained monolayer of MoS\textsubscript{2}. Uniform redshift indicates presence of uniform strain induced by the waveguide ridge.
Subsequently, we study the polarisation dependence of the photoluminescence spectra, which are obtained by parallel excitation of the flake with incident pump light delivered to the material through the waveguide (see call-out in Figure 1a). Polarisation parallel to the flake surface produced maximum excitation (photoluminescence) and conversely, orthogonal polarisation minimised the excitation (see Figure 4a for comparison of intensities). This is in agreement with the two-dimensional nature of the bright excitons, that offer maximum cross section for polarisation of light when it is parallel to the flake.\textsuperscript{20} By rotating the polarisation of the incident light, the excitonic emission is not completely extinguished. Assuming the finite theoretical limit of the extinction, we speculate it is further reduced due to the irregularities in the monolayer surface (introduced during the dry-stamping transfer process), which act as scattering centres, visible in Figure 1d. Similar photoluminescence curves are recorded for intermediate values of polarisation in the increments of 10°. The resultant spectra are integrated, normalised for power (to mitigate the laser instabilities) and plotted against the polarisation angle (Figure 4b). Power for the normalisation is recorded after passing through the chip, at the position of a CCD sensor (Figure 2). The normalised points are then fitted to a sine function that demonstrates the polarisation dependence of photoluminescence with high extinction ratio of 31 between parallel and perpendicular states, which compares favourably with previous reports.\textsuperscript{21}

In addition, we have performed measurements of photoluminescence at the end face of the chip comparing two identical waveguides, one of which contained the flake. The flake generates bright exciton emission at a normal to its plane, which does not couple back into the guided mode and we have indeed observed no resolvable photoluminescence signal at the output of the waveguide. Further to this, we aim to extend the experiment to investigate emission of the dark exciton in MoS\textsubscript{2} and other dichalcogenide monolayers,\textsuperscript{1,3} which has the potential for waveguide coupling in our geometry.
Conclusion

We have presented a working prototype of a photonic chip with an atomically thin MoS$_2$ flake, which is encapsulated directly within the single mode of guided laser light. The observed photoluminescence spectra are consistent with the ones present in the literature for monolayers of MoS$_2$. Sensitivity of the photoluminescence signal to polarisation of pump light is shown, with high extinction ratio and exact expected periodicity of 180°. The chip has shown robustness and ease of handling, being reused in multiple experiments over the period of months without any noticeable degradation in the MoS$_2$ flake. Such capabilities can enable further experiments dealing with optically active materials, such as 2D monolayers, nano-diamonds, crystalline and organic single photon emitters, and similar.

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